



AF  
TFW

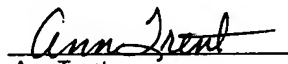
Applicant: Daniel R. Caldwell, et al. Docket No: TI-36721  
Serial No: 10/706,762 Conf. No: 7834  
Examiner: Dung V. Nguyen Art Unit: 3723  
Filed: 11/10/2003  
For: CHEMICAL MECHANICAL POLISHING SLURRY PUMP MONITORING SYSTEM AND METHOD

**AMENDMENT PURSUANT TO 37 CFR 1.116**

Mail Stop AF  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**MAILING CERTIFICATE UNDER 37 C.F.R. § 1.8(a)**

I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 5-26-05.

  
Ann Trent

Dear Sir:

Responsive to the Office Action mailed March 25, 2005, in connection with the above identified application, Applicants respectfully submit the following amendments and remarks.